



PATENT

I hereby certify that on the date specified below, this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

igust 23, 2007

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Dinish Chopra and Scott G.

Attorney Docket No.: 500077.12

Meikle

Patent No. : US 6,964,602 B2

Serial No.

: 10/810,036

Issue Date: November 15, 2005

Filed

: March 26, 2004

Title

: METHODS AND APPARATUSES FOR MECHANICAL AND CHEMICAL-MECHANICAL PLANARIZATION OF MICROELECTRONIC-DEVICE

SUBSTRATE ASSEMBLIES ON PLANARIZING PADS

REQUEST FOR CERTIFICATE OF CORRECTION

Certificate

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 AIIG 3 0 2007

of Correction

Sir:

A Certificate of Correction under 35 U.S.C. § 254 is respectfully requested for the above-identified patent in order to correct Patent and Trademark Office errors made during the printing of the patent. The changes in the patent needed to correct the errors are as follows:

Column, Line	Reads	Should Read
Item (57), Line 20	"includes removing unit"	includes a removing unit
Column 2, Line 9	"C—C the substrate 12."	C—C of the substrate 12
Column 2, Line 65	"is over planarized,"	is over-planarized,
Column 6, Lines 22 and 27	"the first-stage"	the first stage

Column 7, Line 64 "the substrate The multi-stage-stage" -- the substrate. The multi-stage-

The above errors for which correction is requested under 35 U.S.C. § 254 were made in the printing of the patent or in the original application. The errors are considered sufficiently important to justify the processing of a Certificate of Correction under 35 U.S.C. § 254. A Form PTO-1050, in duplicate, is enclosed herewith.

The Commissioner is hereby authorized to charge payment of any fees associated with this communication to Deposit Account No. 50-1266. A duplicate copy of this sheet is enclosed.

Favorable consideration of this Request is respectfully requested.

Respectfully submitted,

Date

By:

Edward W. Bulchis, Reg. No. 26,847

Customer No. 27,076
Dorsey & Whitney LLP
1420 Fifth Avenue, Suite 3400
Seattle, WA 98101
(206) 903-8785
Attorney for Applicant(s)

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Enclosures:

Postcard

Form PTO-1050 (+ copy)

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UNITED STATES PATENT AND TRADEMARK OFFICE CERTIFICATE OF CORRECTION

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US 6,964,602 B2

DATED

November 15, 2005

INVENTOR(S)

Dinesh Chopra and Scott G. Meikle

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MAILING ADDRESS OF SENDER:

Patent No. <u>US 6,964,602 B2</u>

DORSEY & WHITNEY LLP 1420 Fifth Avenue, Suite 3400 Seattle, Washington 98101

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FORM PTO-1050 (REV. 3-82)

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